

ABSTRACT

5 A high dynamic range and high precision broadband optical inspection system and method are provided. The system provides capability of optical inspection of patterned and unpatterned substrates in which a very large dynamic range with very high precision is desirable to provide detection of light scattering defects from sub micron to hundreds of microns in size. The system permits high throughput substrate inspection in which the sides, bevels and edges of the substrate may be rapidly or simultaneously inspected for defects.